## WORKSHOP:



Europäische Forschungsgesellschaft Dünne Schichten e. V. European Society of Thin Films

Sputtering for Precision Optics II – Digital Transformation Driven Trends in the Coating Technology

June 11<sup>th</sup> – 12<sup>th</sup>, 2024 Bühler Leybold Optics, Alzenau, Germany

Supported by:







## Introduction

Photonic technologies play a key role in the ongoing trend towards digitalisation in almost all areas of technology and everyday life. Photonic sensors, integrated optics and miniaturised optical systems enable technological innovations, new monitoring methods and process optimisation for the digitalisation and automation of the industrial production.

The production of such optical systems and the development of new markets and applications requires further development of technologies and the in-depth characterisation of complex processes in the optical manufacturing. The aim is to design these precisely and cost-effectively and to develop the manufacturing processes. Compared to processes in the electronics production, the effort involved is usually higher due to the significantly greater range of functions, materials and structures. At the same time, an increasing fusion of both areas, e.g. optical functionality at wafer level, can be recognised. This is referred to as Wafer Level Optics.

Innovative production technologies for optical coatings, e.g. for anti-reflective coatings and dielectric mirrors, filters, beam splitters and waveguides are essential for applications in the miniaturized optical systems and integrated optics, for image processing, photonic sensors and in the semiconductor industry. Sputtering technology is one of these modern technologies. In this workshop, we would like to show you new, digitalization driven trends in the technologies and applications and how a wide variety of coating materials with the desired properties can be applied to optics made of glass, metal or other materials.



# PROGRAM\*

## Tuesday, June 11<sup>th</sup>, 2024

#### 11:00 | Participant Registration

12:00 | **Welcome Words & Opening** Dr. Steffen Runkel | Bühler Alzenau GmbH, Germany & Udo Klotzbach | EFDS e.V.

#### Session 1 | Keynotes

12:20 | Trends, Opportunities and Challenges for the Optical Coating Industry

Dr. Mathias Mende | Edmund Optics GmbH, Germany

12:50 | Emerging Applications in Photonics: Optical Thin Films in Semiconductor Devices Dr. Stephan Mingels & Dr. Christian Schindler | Bühler Leybold Optics, Germany

#### 13:20 | Gold Sponsor Company Pitch

André Kayser | Hiden Analytical Europe GmbH, Germany

#### 13:25 | COFFEE BREAK

## Session 2 | Miniaturized and Integrated Optics

14:00 | **Shincron's PVD Technology for Optics and Photonics Integrated Circuit Applications** Dr. Takuya Sugawara | Shincron Co. Ltd., Japan

14:25 | **EUV Multilayer Coatings with NESSY Coaters – Exploring Physical Limits** Dr. Torsten Feigl | optiX fab GmbH, Germany 14:50 | **Thin Film Trends in Integrated Optics** Dr. Ronald Dekker | LioniX International B.V., The Netherlands

15:15 | Miniaturized Substrateless Thin Film Filters for Optics Integration Dr. Gerd-Albert Hoffmann | Laser Zentrum Hannover e.V. (LZH), Germany

#### 15:40 | COFFEE BREAK

#### Session 3 | Imaging and Sensors

#### 16:00 | Microwave Plasma Assisted Deposition of Optical Coatings and Applications in Photonic Sensors and Imaging

Prof. Dr. Des Gibson | University of the West of Scotland & Albasense Ltd, United Kingdom

#### 16:25 | Optical Precision on the Reverse Side: Requirements and Solutions for Double-Sided Coatings

Michael Schneider | Von Ardenne GmbH, Germany & Stefan Bruns | Fraunhofer Institute for Surface Engineering and Thin Films IST, Germany

### 16:50 | Photolithographic structuring of complex PARMS filters

Marc Lappschies | Optics Balzers Jena GmbH, Germany

#### 17:15 | Wafer Level Patterning of Optical Filters: Seeing Things Differently.

Wouter Charle | imec, Belgium

#### 17:40 | Summary of the First Workshop Day

17:50 | End of 1st Workshop Day

#### **GET TOGETHER**

19:00 – 22:00 | **JOINT DINNER** 



# PROGRAM\*

## Wednesday, June 12<sup>th</sup>, 2024

08:20 | Registration

## Completion Session 3 | Imaging and Sensors

#### 08:35 | Challenges in High Quality and Low Defect Mirror Depositions for MEMS Applications

Maria Esperanza Navarro Fuentes | Fraunhofer Institute for Photonic Microsystems IPMS, Germany

#### Session 4 | Trends & Innovations I

## 09:00 | Multilayer Coating for Femtosecond and Attosecond Physics

Dr. Vladimir Pervak | Ludwig-Maximilians-Universität München, Germany

#### 09:25 | Light-Tunable Optical Metasurfaces

Dr. Purushottam Poudel | Friedrich-Schiller-University Jena, Germany

#### 09:50 | Target Materials - A Vital Role in Coating Operations, Looking at Quality and Sustainability

Alfred Willer | Sindlhauser Materials GmbH, Germany

#### 10:15 | COFFEE BREAK

#### Session 5 | Trends & Innovations II

11:15 | Semiconductor Deposition Equipment for Precision Optics Dr. Taguhi Yeghoyan | Yole Group, France

#### 11:40 | Measuring Ultra-Low Optical Losses in Optical Materials and Coatings: The Key to Process Improvement

Dr. Christian Mühlig | Fraunhofer Institute for Applied Optics and Precision Engineering IOF, Germany

#### 12:05 | Photonic Technologies as an Indispensable Key Enabler for Innovations in Quantum Technology.

Dr. Bernd Jungbluth | Fraunhofer Institute for Laser Technology ILT, Germany

#### 12:30 | LUNCH BREAK

#### Session 6 | Interactive Exchange

13:30 | Discussion on Research &Cooperation NeedsModeration by Dr. Christian Schindler | BühlerLeybold Optics & Participants

13:55 | Guided Tour through the Bühler Leybold Optics "Application Center for Thin-Film Solutions" the participants split into groups

#### 15:30 | END OF THE WORKSHOP





## GENERAL

#### **Participant fees**

Early bird ticket (Standard) until April 10, 2024	730 EUR
Participation ticket (Standard) from April 11, 2024	830 EUR
Participation ticket (Student) Please send us a copy of your valid student ID to <u>info@efds.org</u> .	420 EUR
Participation fees are tax-free according to §4 (22a) UStG.	

#### **Online Registration**

Please register on the website https://efds.org/en/event/workshop-optic-ii/



#### **Event Location**

Bühler Alzenau GmbH Siemensstraße 88 63755 Alzenau, Germany

#### **Event Management**

#### Europäische Forschungsgesellschaft Dünne Schichten e.V. (EFDS e.V.)

European Society of Thin Films

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#### Workshop Committee:

Dr. Christian Schindler | Bühler Leybold Optics

Dr. Diana Tonova | Carl Zeiss Jena GmbH

Dr. Adriana Szeghalmi | Fraunhofer IOF Jena

Uwe Heydenreich | TRUMPF Hüttinger GmbH + Co. KG

Anja Härtel | EFDS e.V.

#### Data protection declaration

We would like to inform you that the event will be documented photographically. By participating, you agree that all pictures taken may be used by the EFDS for communication and marketing purposes. In accordance with your consent when registering online, a list of participants with names and company affiliation will be compiled and published exclusively in the conference proceedings. The data will be collected in accordance with the privacy policy of the European Society of Thin Films. The data protection declaration can be found at

https://efds.org/en/privacy-policy-2/.